

In the Abstract:

~~The invention relates to a~~ A device for carrying out gas reactions, comprising a plasma reactor with a through-flow of gases which has a, particularly cylindrical, plasma chamber, wherein flow-forming elements for forming a flow of gases are arranged before and/or in and/or after the plasma reactor in order to form a gas stream within the plasma chamber such that at least one, particularly central, zone in the gas flow is formed which is flow-reduced. ~~The invention further relates to a~~ A method for carrying out gas reactions is also provided.

~~Figure 2.~~